

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L3	1	"20030095307".pn.	US-PGPUB; USPAT	OR	ON	2006/01/09 11:22
L1	548	((359/214,224,290,291,295,298) (385/15,18) (310/309)).ccls. and @pd>="20050613"	US-PGPUB; USPAT	OR	ON	2006/01/09 11:22
L2	454572	mem mems micromechanical microelectromechanical microelectricalmechanical (micro adj2 mechanical) (micro adj2 electro adj2 mechanical) (micro adj2 electrical adj2 mechanical)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/09 11:39
L4	54	2 and ((modify\$3 chang\$3 reconfigur\$3) near3 (software algorithm (bit near2 map)) same (channel wavelength\$1))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/09 11:47
L6	26	4 and (mirror\$1 micromirror\$1 (micro near2 mirror\$1))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/09 12:07
L10	1498	mems and (tilt\$4 near3 (mirror micromirror))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/09 12:10
L14	128	10 and (circuit\$2 with (form\$3 fabricat\$3) with (semiconductor silicon) with substrate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/09 12:52
L11	247	10 and (circuit\$2 with (form\$3 fabricat\$3) with substrate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/09 12:52